

IN THE SPECIFICATION:

Please delete paragraph [0030] and replace it with the following paragraph:

[0030] Substrate 135 can be affixed to the substrate holder 130 via an electrostatic clamping system. For example, an electrostatic clamping system can comprise an electrode [[116]] 117 and an ESC supply 156. Clamping voltages, that can range from approximately -2000 V to approximately +2000 V, for example, can be provided to the clamping electrode. Alternatively, the clamping voltage can range from approximately -1000 V to +1000 V. In alternate embodiments, gas can, for example, be delivered to the backside of substrate 135 via a backside gas system to improve the gas-gap thermal conductance between substrate 135 and substrate holder 130. In other alternate embodiments, lift pins can be provided in substrate holder 130.

Please delete paragraph [0032] and replace it with the following paragraph:

[0032] Also, a lower electrode 116 can be coupled to a second RF source 160 using a second match network 162. Alternately, a match network is not required.